



IFW

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Kazuo ICHIKAWA et al.

Group Art Unit: 1763

Application No.: 09/670,877

Examiner: R. ZERVIGON

Filed: September 27, 2000

Docket No.: 107469

For: CVD SYSTEM AND Substrate Cleaning Method

AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In reply to the March 17, 2006 Office Action, please consider the following:

Amendments to the Claims as reflected in the listing of claims; and

Remarks.